Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A piezoelectric/electrostrictive film device comprising:

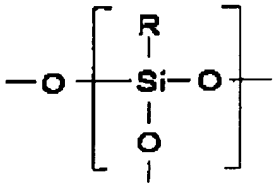
a substrate which is formed of ceramic; ~~and~~

a piezoelectric/electrostrictive operation portion including a lower electrode, piezoelectric/electrostrictive layer, and upper electrode which are successively stacked on the substrate and including a projecting end of the piezoelectric/electrostrictive layer with which an upper surface of the lower electrode and a lower surface of the upper electrode are not coated~~, wherein~~; and

a coupling member extending between said~~a~~ projecting ~~portion~~end of the piezoelectric/electrostrictive layer and the substrate and being coupled to the substrate, wherein the~~is a~~ coupling member ~~constituted of~~comprises a hybrid material in which ~~inorganic~~silica particles are scattered in a matrix containing a polysiloxane polymer as a main component~~of a polymer compound, and is coupled to the substrate~~.

Claim 2 (Cancelled)

3. (Currently Amended) The piezoelectric/electrostrictive film device according to claim ~~2~~1, wherein the polysiloxane polymer is a polysiloxane polymer in which a substituent group is introduced in a part shown in the following general formula (1):



····· (1)

where R is at least one alkyl group selected from a group consisting of a methyl group, ethyl group, and propyl group, an aryl group, an alkenyl group, or at least one

substituent alkyl group selected from a group consisting of a γ-methacryloxypropyl group, γ-glycidoxypropyl group, γ-chloropropyl group, γ-mercaptopropyl group, γ-aminopropyl group, and trifluoromethyl group.

4. (Currently Amended) ~~The~~A piezoelectric/electrostrictive film device comprising:~~according to claim 1, wherein an average particle diameter of the inorganic particles is in a range of 5 nm to 1 μm.~~

a substrate which is formed of ceramic;

a piezoelectric/electrostrictive operation portion including a lower electrode, piezoelectric/electrostrictive layer, and upper electrode which are successively stacked on the substrate and including a projecting end of the piezoelectric/electrostrictive layer with which an upper surface of the lower electrode and a lower surface of the upper electrode are not coated; and

a coupling member extending between said projecting end of the piezoelectric/electrostrictive layer and the substrate and being coupled to the substrate, wherein the coupling member comprises a hybrid material in which inorganic particles having an average particle diameter of 5 nm to 1μm are scattered in a matrix of a polymer compound.

5. (Original) The piezoelectric/electrostrictive film device according to claim 4, wherein the inorganic particles have a two-peaks particle size distribution, and a ratio (D/C) of an average particle diameter (C) of large-diameter inorganic particles having a particle diameter larger than that corresponding to a inflection point existing between two peaks to an average particle diameter (D) of small-diameter inorganic particles having a particle diameter not more than that corresponding to the inflection point is in a range of 0.05 to 0.7.

6. (Currently Amended) A piezoelectric/electrostrictive film device comprising:

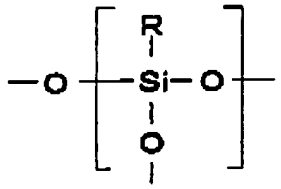
a substrate which is formed of ceramic;~~, and~~

a piezoelectric/electrostrictive operation portion including a plurality of electrodes and a plurality of piezoelectric/electrostrictive layers which are alternately stacked on the substrate and including a projecting end of each piezoelectric/electrostrictive layer with which upper and lower surfaces of each electrode are not coated~~, wherein~~; and

a coupling member extending between said projecting ~~portion~~end of the piezoelectric/electrostrictive layer and the substrate and being coupled to the substrate, wherein the~~is a~~ coupling member ~~constituted of~~comprises a hybrid material in which ~~inorganic~~silica particles are scattered in a matrix containing a polysiloxane polymer as a main component~~of a polymer compound, and is coupled to the substrate~~, and the electrodes are disposed in uppermost and lowermost layers in a multilayered structure of the piezoelectric/electrostrictive layers and electrodes.

Claim 7 (Cancelled)

8. (Currently Amended) The piezoelectric/electrostrictive film device according to claim ~~7~~6, wherein the polysiloxane polymer is a polysiloxane polymer in which a substituent group is introduced in a part shown in the following general formula (1):



····· (1)

where R is at least one alkyl group selected from a group consisting of a methyl group, ethyl group, and propyl group, an aryl group, an alkenyl group, or at least one substituent alkyl group selected from a group consisting of a γ-methacryloxypropyl group, γ-glycidoxypropyl group, γ-chloropropyl group, γ-mercaptopropyl group, γ-aminopropyl group, and trifluoromethyl group.

9. (Currently Amended) A~~The~~ piezoelectric/electrostrictive film device ~~according to claim 6, wherein an average particle diameter of the inorganic particles is in a range of 5 nm to 1 μm~~comprising:

a substrate which is formed of ceramic;

a piezoelectric/electrostrictive operation portion including a plurality of electrodes and a plurality of piezoelectric/electrostrictive layers which are alternately stacked on the substrate and including a projecting end of each piezoelectric/electrostrictive layer with which upper and lower surfaces of each electrode are not coated; and

a coupling member extending between said projecting end of the piezoelectric/electrostrictive layer and the substrate and being coupled to the substrate, wherein the coupling member comprises a hybrid material in which inorganic particles having an average particle diameter of 5 nm to 1μm are scattered in a matrix of a polymer compound, and the electrodes are disposed in uppermost and lowermost layers in a multilayered structure of the piezoelectric/electrostrictive layers and electrodes.

10. (Original) The piezoelectric/electrostrictive film device according to claim 9, wherein the inorganic particles have a two-peaks particle size distribution, and a ratio (D/C) of an average particle diameter (C) of large-diameter inorganic particles having a particle diameter larger than that corresponding to a inflection point existing between two peaks to an average particle diameter (D) of small-diameter inorganic particles having a particle diameter not more than that corresponding to the inflection point is in a range of 0.05 to 0.7.

Claims 11-23 (Cancelled)